

Supporting Information

Unveiling the Dynamics of Self-Assembled Layers of Thin Films of PVME by Nanosized Relaxation Spectroscopy

*Sherif Madkour¹, Paulina Szymoniak¹, Mojdeh Heidari², Regine von Klitzing², Andreas
Schönhals^{1*}*

¹ Bundesanstalt für Materialforschung und –prüfung - (BAM),
Unter den Eichen 87, 12205 Berlin (Germany)

²Stranski-Laboratorium für Physikalische und Theoretische Chemie/ Institut für Chemie,
Technische Universität Berlin, Straße des 17. Juni 124, 10623 Berlin (Germany)

*CORRESPONDING AUTHOR

Email: Andreas.Schoenhals@bam.de

Atomic force microscopy (AFM)

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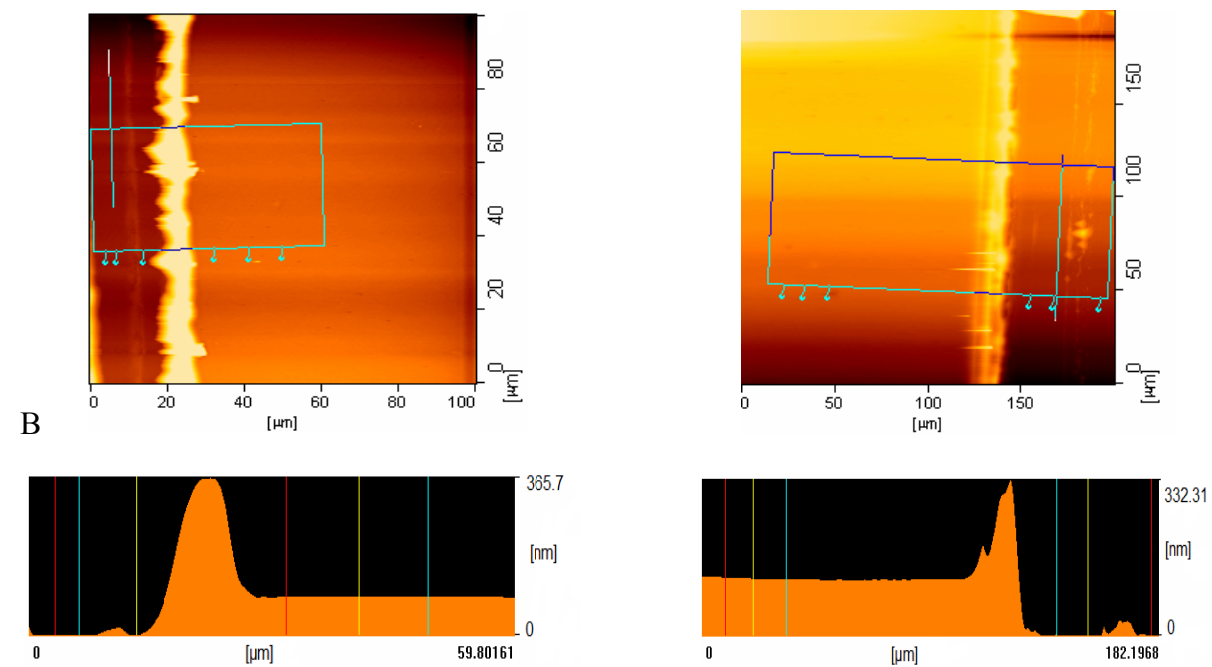


Figure S1: AFM image of a scratch across (left) the Al-electrode and (right) PVME film on the same Al-electrode (A), cross section view (B) of the rectangular area indicating that the average thickness of the film in the marked scratch was ca. 50 nm. No sign of dewetting was found.

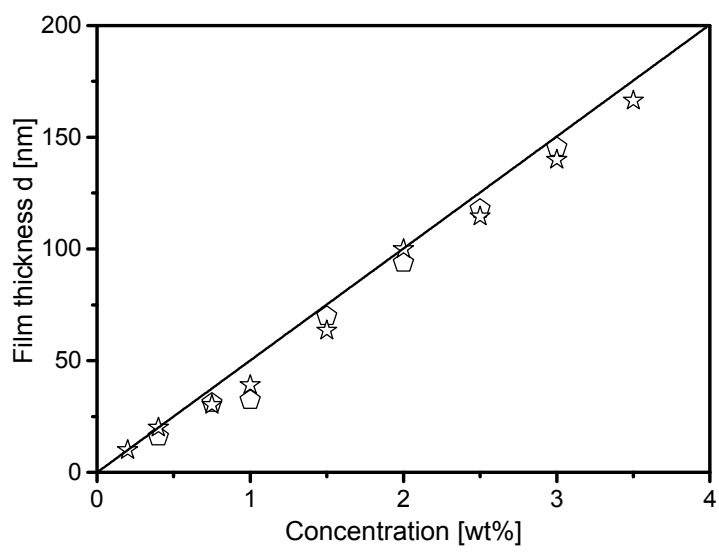


Figure S2: Film thickness versus concentration of the polymer solution. Stars - ellipsometry thicknesses of PVME; black circles - thickness values estimated by AFM. The solid red line represents a common linear regression of the data.

Broadband dielectric spectroscopy (BDS)

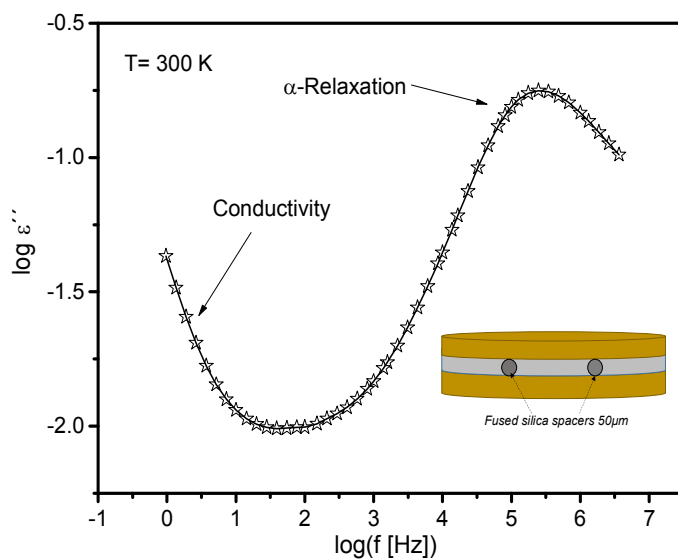


Figure S3. Dielectric loss spectra for bulk PVME at 300 K- stars. The solid line is a fit of equation 3 to the data. Inset: Schematic of the sample geometry used to measure bulk PVME.

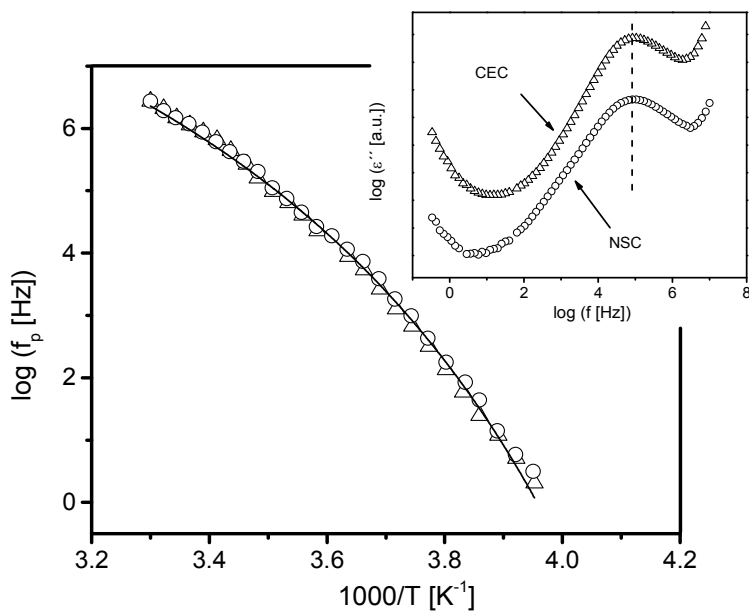


Figure S4. Relaxation map of ca. 50 nm PVME films measured by CEC –triangles and NSC –circles. The solid line is a common VFT fit to the data. Inset: Dielectric loss spectra at 293 K for a ca. 50 nm PVME ultrathin film using the CEC - triangles and NSC – circles. The curves are shifted along the y-scale for sake of cleanness.

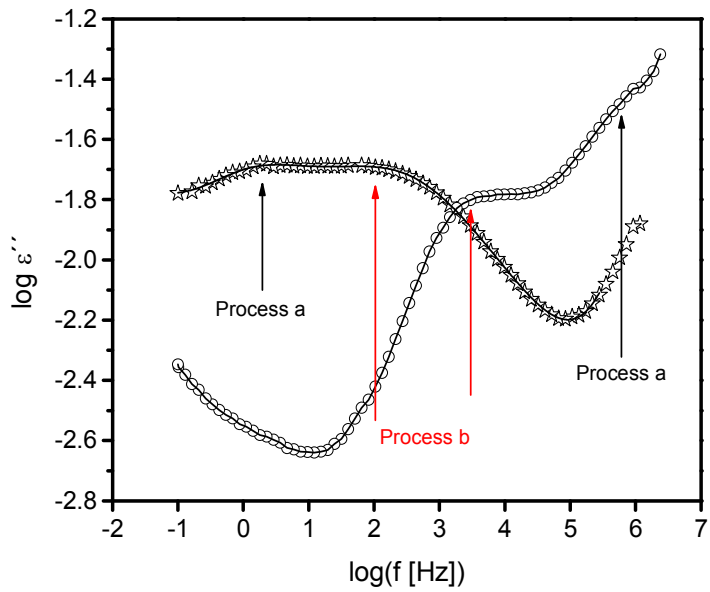


Figure S5. Dielectric loss spectra at 305 K -circles and 253 K -stars for a ca. 7 nm PVME thin film using the NSC. The solid lines are fits for the data using equation 3. Process (a) α -relaxation of PVME and process (b) the relaxation of the segments within the part of the adsorbed layer with logarithmic time dependence.

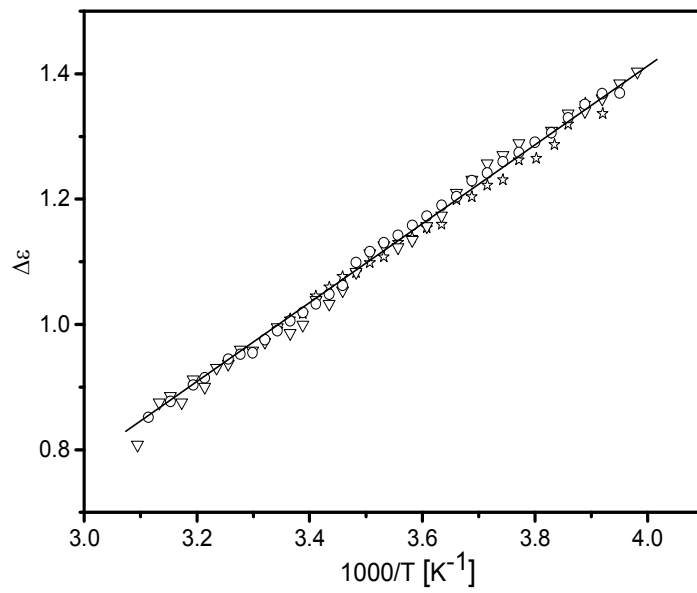


Figure S6. Dielectric strength for PVME ultrathin films in CEC with thicknesses of 160 nm– circles, 110 nm– upside triangles and 50 nm – stars. The solid lines are linear fits to the data.

Contact angle measurements (CAM)

$$(1 + \cos \theta_i) \gamma_{L,i} = 2[(\gamma_{PVME}^{LW} \gamma_{L,i}^{LW})^{\frac{1}{2}} + (\gamma_{PVME}^+ \gamma_{L,i}^-)^{\frac{1}{2}} + (\gamma_{PVME}^- \gamma_{L,i}^+)^{\frac{1}{2}}] \quad (S1)$$

$$a_i \gamma^{PVME} = 2[b_i (\gamma_{PVME}^{LW})^{\frac{1}{2}} + c_i (\gamma_{PVME}^+)^{\frac{1}{2}} + d_i (\gamma_{PVME}^-)^{\frac{1}{2}}] \quad (S2)$$

$$\frac{(1 + \cos \theta_i) \gamma_{L,i}}{2 \sqrt{\gamma_{L,i}^{LW}}} = \sqrt{\gamma_S^P} \frac{\sqrt{\gamma_{L,i}^P}}{\sqrt{\gamma_{L,i}^{LW}}} + \sqrt{\gamma_S^{LW}} \quad (S3)$$

Test liquids	Contact angle
Glycerol	89.9°
HDEC	13.3°
PEG	64.6°
TDEC	7.4°

Table S1: Contact angle values of the test liquids used for poly(vinyl methyl ether).

	γ^{Total} [mJ m ⁻²]	γ^{LW} [mJ m ⁻²]	γ^P [mJ m ⁻²]
PVME	27.4	26.01	1.36
AlO ₂	30.4	26.5	3.9
SiO ₂	47.0	44.6	2.3

Table S2: Total surface energies γ^{Total} and their dispersive γ^{LW} and polar γ^P components for PVME, SiO₂ and AlO₂ surfaces of the capacitors.

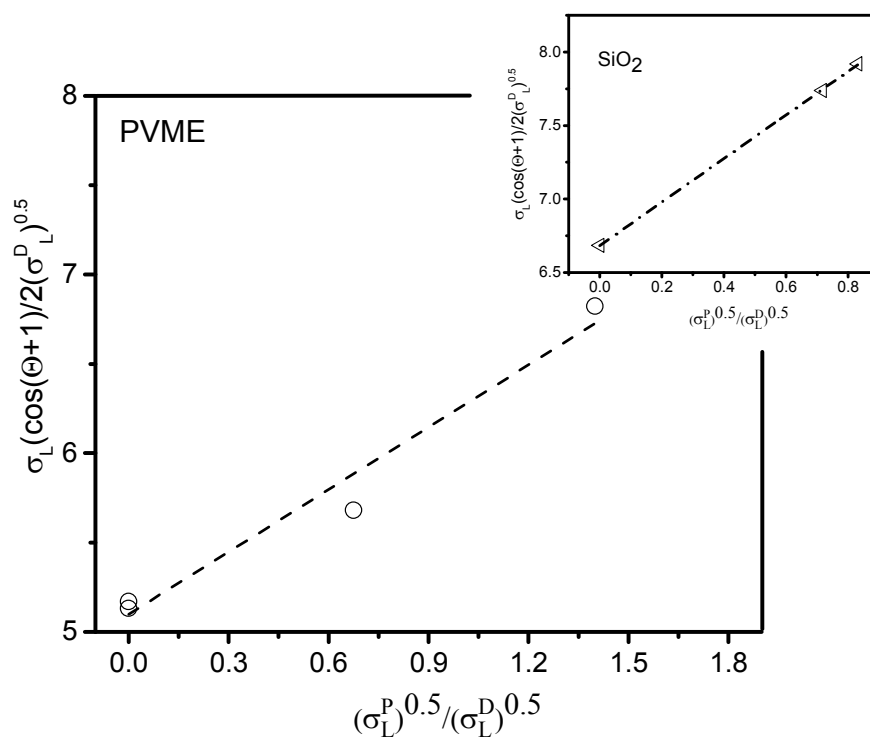


Figure S7. Owens/Wendt plot according to Equ. (S3). The polar and dispersive components of the solid surface energy are estimated by linear regression. Results are presented in Table S1.